

Notice of References Cited

Application/Control No.

10/797,231

Applicant(s)/Patent Under

Reexamination

HAMMOND ET AL.

Examiner

Alexander G. Ghyka

Art Unit

2812

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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	C	US-			
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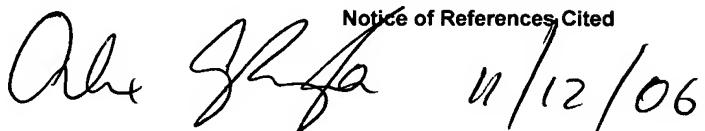
FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
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	V	Chang et al, Selective Etching of SiGe on SiGe/Si Heterostructures, J. Electrochem, Soc. Vol. 138, No.1, 1991
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 11/12/06